

ABSTRACT

5 Disclosure relates to a substrate processing apparatus that can quickly transport a substrate
to a cleaning module after surface processing of the substrate is performed. The substrate processing
apparatus includes processing units each for processing a substrate and a relay transporter that
transports the substrate between the processing units. Each processing unit includes a surface-
processing module, a cleaning module, a drying module, a substrate transporter extending from one
10 side to opposite side of each processing unit, and a processing transporter that transports the substrate
from the substrate transporter to the surface-processing module and from the surface-processing
module to the cleaning module.

FIG. 1